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Dr. Jaeho Kim is now a senior research scientist in the Electronics and Photonics Research Institute at National Institute of Advanced Science and Technology (AIST). He has over 20 years of research experience for both fundamental aspects and industrial applications of plasma processing for the synthesis of carbon nanomaterials.

He graduated from the Kyungpook National University with the major of Electrical Engineering in 1998. For 1999 – 2003, he studied in the University of Tokyo for his master and Ph.D. degrees. After finishing his graduate study, he joined the University of Tokyo as a research associate. In 2006, he joined AIST to study plasma processing technologies and industrial applications of carbon nanomaterials such as nanocrystalline diamond, graphene and CNT. From Jul. 2019 to Jul. 2020, he stayed in the University of Colorado - Boulder as a visiting scholar to study atomic layer deposition (ALD) and atomic layer etching (ALE) technologies. He is now developing innovative plasma ALD & ALE processes for the achievement of high-performance electronic devices based on carbon nanomaterials. As well as, he has attended several joint research projects for the studies on plasma applications including plasma medicine, surface treatments, nitriding of metal surfaces and nitride-semiconductor optical devices.

He is a member of the Institute of Electrical Electronics Engineers (IEEE), the Institute of Electrical Engineers of Japan (IEEJ), the Japan Society of Applied Physics (JSAP) and the Materials Research Society of Japan (MRS-J). He served as a secretary of the division of plasma electronics in JSAP for 2012 - 2013, a secretary of the technical committee on plasma science and technology in IEEJ for 2012 - 2014, and a vice chair and chair of the IEEE Nuclear and Plasma Society Japan Chapter in 2013 and 2014, respectively. He has served as a member of Investigating R&D committee for plasma surface technology in IEEJ since 2019, an associate editor of the Journal of Electrical Engineering & Technology (JEET) since 2017 and a co-organizer for the international symposium “Frontier of Nano-Materials Based on Advanced Plasma Technology” in annual meeting of MRS-J since 2013.